

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:)	
)	Group Art Unit: 2112
Shinichiro Nohdo)	
)	Examiner: Rebecca Slomski
Application No. 11/812,602)	
)	
Filed: March 30, 2004)	
)	
For: WAFER, EXPOSURE MASK, METHOD OF)	
DETECTING MARK AND METHOD OF)	
EXPOSURE)	

Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-1450

RESPONSE TO ELECTION/RESTRICTION REQUIREMENT

Dear Sir:

This amendment is being filed in response to the Office communication dated October 27, 2006. Please reconsider the application in view of the amendment and remarks presented below.

ELECTION OF CLAIMS

In response to the election requirement, applicant hereby elects Group I, Claims 1-8 for further examination.

Applicant reserves the right to file divisional applications covering the subject matter of the non-elected claims and/or to request rejoinder of non-elected claims.

Dated: Nov. 20, 2006

Respectfully submitted,
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